

**Amendment and Response**

Applicant: Norman L. Oberski et al.

Serial No.: 10/6232,848

Filed: July 18, 2003

Docket No.: A126.113.102

Title: INSPECTION TOOL WITH A 3D POINT SENSOR TO DEVELOP A FOCUS MAP

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**IN THE ABSTRACT**

Please replace the paragraph beginning at page 9, line 4, with the following, re-written paragraph:

**Abstract of the Disclosure**

An inspection system, and process for use thereof, ~~allows~~for inspecting of semiconductors or like substrates. The inspection system includes an inspection device and an auxiliary sensor apart from the inspection device. The auxiliary sensor is used to collect height data and generate a map of a semiconductor or like substrate to aids in focusing the inspection device.